



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:  
Philip J. Ireland

Serial No.: 10/676,066

Filed: September 30, 2003

For: **CAPACITIVE COUPLING REDUCTION  
USING VOID FORMATION FOR USE  
WITH A SEMICONDUCTOR DEVICE**

§  
§ Group Art Unit: 2813  
§  
§ Examiner: Thanhha S. Pham  
§  
§ Atty. Docket: 2000-0995.01/US  
§  
§ Confirmation No.: 7725  
§  
§

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Date

Muriel Helms  
Signature

**COMMENTS ON STATEMENT OF REASONS FOR ALLOWANCE**

Applicant submits that each one of the claims of the captioned application is allowable over the cited art for reason of the cited art failing to disclose or suggest the features and/or combination of features as are defined therein. Although applicant acknowledges the Examiner's "Statement of Reasons for Allowance" as set forth with the Notice of Allowance dated February 16, 2005, applicant submits that the reasons for allowance as provided by the Examiner may represent merely a portion of all of the reasons that support the patentability of the claims of the present application without necessarily being exhaustive.

If there are any matters which may be resolved or clarified through a telephone call, the Examiner is cordially invited to contact the undersigned.

Respectfully submitted,

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